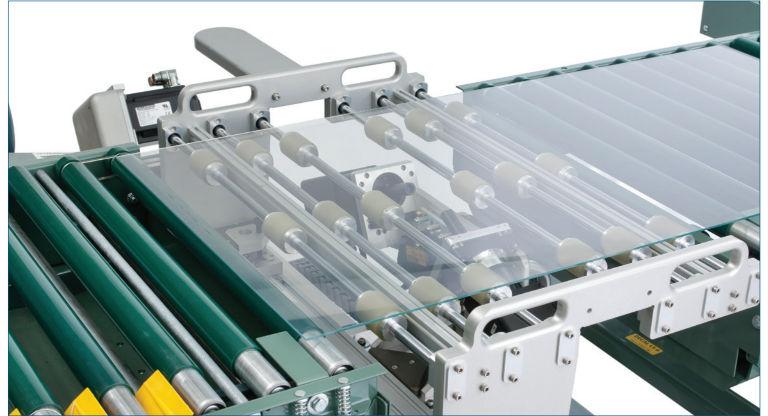
Introducing the NEW...

InLine-SE

The proven capability of our M-2000® line of spectroscopic ellipsometers can now be applied to in-line systems. The InLine-SE has been developed to measure films on glass panels as they move down a conveyor line. It can be mounted above or below the substrate.



InLine ellipsometer measuring a film on a glass panel.

Features

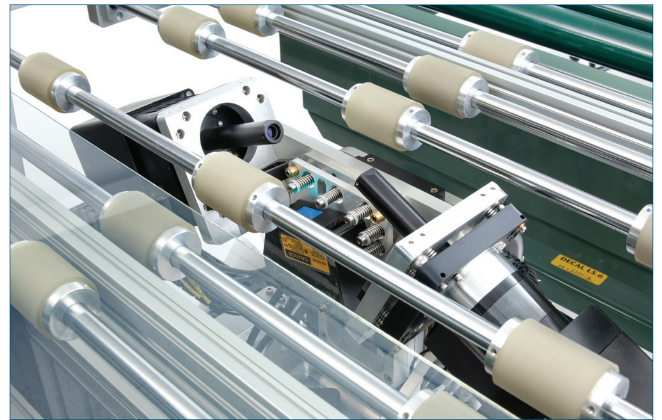
Advanced Ellipsometer Technology

Patented RCE (rotating compensator ellipsometer) technology to achieve high accuracy and precision.

Fast Spectral Detection

The RCE design is compatible with advanced CCD detection to measure ALL wavelengths simultaneously. Typical measurements require 0.5 to 2 seconds for full spectrum per location.*

**Optimal measurement speed depends on sample reflectivity, desired scan pattern, and other factors.*



Close-up of InLine ellipsometer on a conveyor belt.

Wide Spectral Range

Collect several hundred wavelengths from the visible to the near infrared – all simultaneously.

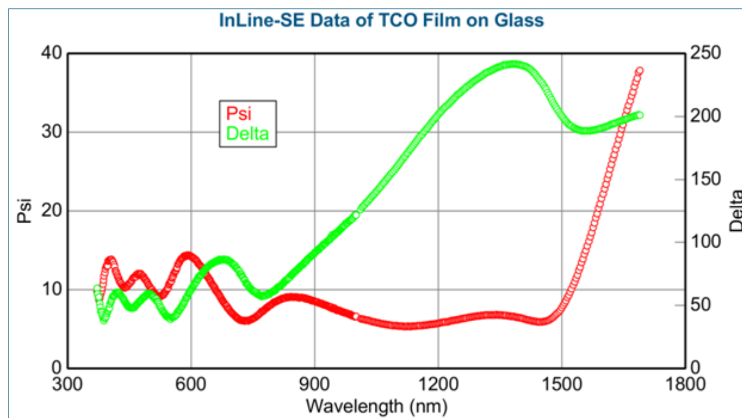


Figure 1. Each circle represents one measured wavelength.

Lateral Scanning

The InLine-SE has translation capability to scan laterally and monitor uniformity across the entire substrate width.

Precisely Controlled Z Height

Real-time feedback allows the InLine-SE to maintain proper working distance within a few micrometers, even if there is some substrate warpage and vibration.

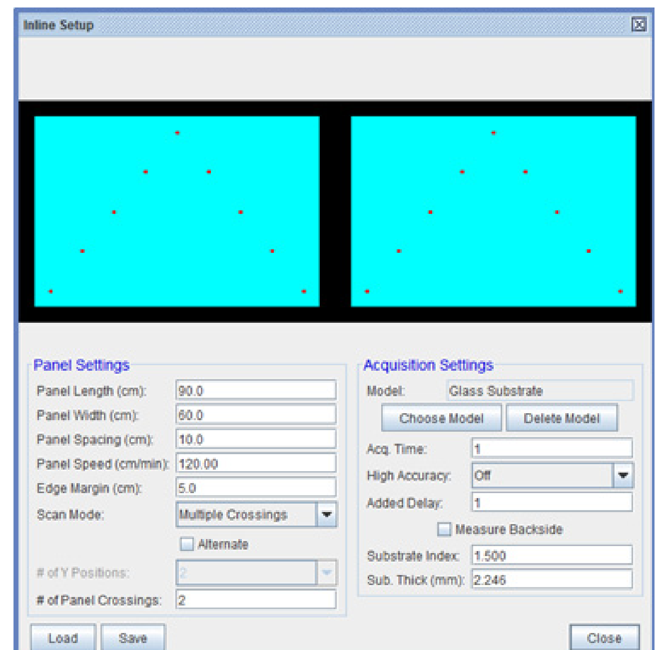


Figure 2. User can choose scan mode (e.g. multiple crossings) to laterally scan across width of panel.